WEST Search History

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DATE: Thursday, August 25, 2005

Hide?	Set Name	Query	Hit Count
		DB=PGPB,USPT,USOC; PLUR=YES; OP=ADJ	
☐	L20	L19 and (semiconductor or chamber or etch$3 or CVD)	17
☐	L19	L18 and l14	48
☐	L18	((pip$5 or tub$5 or line or exhaust$3 or valve) with (clean$3 or wash$3)) same (IPA or isopropanol or hexane or acetone or toluene or methanol)	7487
		DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ	
☐	L17	l9 and (semiconductor or CVD or PVD or etch$3)	8
		DB=PGPB,USPT,USOC; PLUR=YES; OP=ADJ	
☐	L16	L14 and l8	8
☐	L15	L14 and 539	6
☐	L14	134/22.1,22.11,22.12,22.14,22.18,22.19.ccls.	3136
☐	L13	l8 and l11	2
☐	L12	134/22.1,31,19,34,35,40.ccls.	5426
☐	L11	134/22.1.ccls.	1008
		DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ	
☐	L10	134/22.1,31,19,34,35,40.ccls.	440
☐	L9	(apparatus or system) same ((pip$5 or tub$5 or line or exhaust$3 or valve) with (clean$3 or wash$3) with (IPA or iso-propanol or hexane or acetone or toluene or methanol))	32
		DB=PGPB,USPT,USOC; PLUR=YES; OP=ADJ	
☐	L8	L7	539
		DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ	
☐	L7	(apparatus or system) same ((pip$5 or tub$5 or line or exhaust$3 or valve) with (clean$3 or wash$3) with (IPA or iso-propanol or hexane or acetone or toluene or methanol))	571
☐	L6	((apparatus or system) with (CVD or PVD)) same ((pip$5 or tub$5 or exhaust$3 or valve) with (clean$3 or wash$3) with (IPA or iso-propanol or hexane or acetone or toluene or methanol))	1
☐	L5	((apparatus or system) with semiconductor) same ((pip$5 or tub$5 or exhaust$3 or valve) with (clean$3 or wash$3) with (IPA or iso-propanol or hexane or acetone or toluene or methanol))	7
☐	L4	L3 and (clean$3 or wash$3)	1
☐	L3	lin-chi-hui$.in.	67
☐	L2	L1 and (clean$3 or wash$3)	3

☐   L1   nanmat technology   12

END OF SEARCH HISTORY